What is claimed is:

1. An active-drive type pixel structure comprising at least: TFT for control by which control output is generated, based on potential of a data line; TFT for drive in which a driving electric current is controlled, based on the control output; and a capacitor for charge retention in which the control output is temporarily maintained, wherein

one terminal of a dummy load for inspection is connected to an electric output terminal of the TFT for drive, and the other terminal of the dummy load is connected to a line for inspection.

2. An active-drive type pixel structure comprising at least: TFT for control by which control output is generated, based on potential of a data line; TFT for drive in which a driving electric current is controlled, based on the control output; and a capacitor for charge retention in which the control output is temporarily maintained, wherein

one terminal of a dummy load for inspection is connected to an electric output terminal of the TFT for drive, and the other terminal of the dummy load is connected to a gate of the TFT for drive.

3. An active-drive type pixel structure comprising at least: TFT for control by which control output is generated, based on potential of a data line; TFT for drive in which a driving electric current is controlled, based on the control output;

and a capacitor for charge retention in which the control output is temporarily maintained, wherein

one terminal of a dummy load for inspection is connected to an electric output terminal of the TFT for drive, and the other terminal of the dummy load is connected to a source or a gate of the TFT for control.

4. An inspection method of an active-drive type pixel structure which comprises at least: TFT for control by which control output is generated, based on potential of a data line; TFT for drive in which a driving electric current is controlled, based on the control output; and a capacitor for charge retention in which the control output is temporarily maintained, and in which one terminal of a dummy load for inspection is connected to an electric output terminal of the TFT for drive, and the other terminal of the dummy load is connected to a line for inspection, wherein the method has:

a step in which the TFT for control is put into an ON state; and

a step in which a value of an electric current passing in the dummy load for inspection is measured while changing any one of a gate voltage, or a source one of the TFT for drive, or a line voltage of a line for inspection or changing two or more of the voltages in a relative manner to one another.

5. The inspection method of an active-drive type pixel structure according to claim 4, wherein

the dummy load for inspection is processed to be put into

a high impedance state after the step in which the value of the electric current passing in the dummy load for inspection is measured.

6. The inspection method of an active-drive type pixel structure according to claim 5, wherein

means for destroying the dummy load for inspection by a laser beam is adopted as means by which the dummy load for inspection is processed to be put into the high impedance state.

7. The inspection method of an active-drive type pixel structure according to claim 5, wherein

means for fusing the dummy load for inspection by passing a predetermined electric current in the dummy load for inspection is adopted as means by which the dummy load for inspection is processed to be put into the high impedance state.

8. An inspection method of an active-drive type pixel structure which comprises at least: TFT for control by which control output is generated, based on potential of a data line; TFT for drive in which a driving electric current is controlled, based on the control output; and a capacitor for charge retention in which the control output is temporarily maintained, and in which one terminal of a dummy load for inspection is connected to an electric output terminal of the TFT for drive, and the other terminal of the dummy load is connected to a gate of the TFT for drive, wherein the method has:

a step in which the TFT for control is put into an ON state; and

a step in which a value of an electric current passing in the dummy load for inspection is measured while changing either of a gate voltage, or a source one of the TFT for drive, or changing both of the voltages in a relative manner to each another.

9. The inspection method of an active-drive type pixel structure according to claim 8, wherein

the dummy load for inspection is processed to be put into a high impedance state after the step in which the value of the electric current passing in the dummy load for inspection is measured.

10. The inspection method of an active-drive type pixel structure according to claim 9, wherein

means for destroying the dummy load for inspection by a laser beam is adopted as means by which the dummy load for inspection is processed to be put into the high impedance state.

11. The inspection method of an active-drive type pixel structure according to claim 9, wherein

means for fusing the dummy load for inspection by passing a predetermined electric current in the dummy load for inspection is adopted as means by which the dummy load for inspection is processed to be put into the high impedance state.

12. An inspection method of an active-drive type pixel structure which comprises at least: TFT for control by which control output is generated, based on potential of a data line; TFT for drive in which a driving electric current is controlled, based on the control output; and a capacitor for charge retention in which the control output is temporarily maintained, and in which one terminal of a dummy load for inspection is connected to an electric output terminal of the TFT for drive, and the other terminal of the dummy load is connected to a source or a gate of the TFT for control, wherein the method has:

a step in which the TFT for control is put into an ON state; and

a step in which a value of an electric current passing in the dummy load for inspection is measured while changing any one of the gate voltage or the source one of the TFT for drive, or a voltage at the other terminal of the dummy load, or changing two or more of the voltages in a relative manner to one another.

13. The inspection method of an active-drive type pixel structure according to claim 12, wherein

the dummy load for inspection is processed to be put into a high impedance state after the step in which the value of the electric current passing in the dummy load for inspection is measured.

14. The inspection method of an active-drive type pixel structure according to claim 13, wherein

means for destroying the dummy load for inspection by a laser beam is adopted as means by which the dummy load for inspection is processed to be put into the high impedance state.

15. The inspection method of an active-drive type pixel structure according to claim 13, wherein

means for fusing the dummy load for inspection by passing a predetermined electric current in the dummy load for inspection is adopted as means by which the dummy load for inspection is processed to be put into the high impedance state.